
Surface chemical analysis — Depth profiling — Measurement of sputtered depth

*Analyse chimique des surfaces — Profilage d'épaisseur — Mesurage
de l'épaisseur bombardée*

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Contents

Page

Foreword	iv
Introduction	v
1 Scope	1
2 Normative references	1
3 Terms and definitions	1
4 Methods of determination of the sputtered depth	2
4.1 Crater depth measurement after sputter profiling.....	2
4.1.1 General description.....	2
4.1.2 Mechanical stylus crater depth measurement.....	2
4.1.3 Optical interferometry crater depth measurement.....	3
4.2 Comparison with sputter profiled samples having interfaces as depth markers.....	5
4.2.1 General description.....	5
4.2.2 Reference materials.....	5
4.2.3 Interface depth determination for layered structures by independent measurements.....	6
4.3 Typical applications and uncertainties of the different methods.....	10
Annex A Survey of typical applications and uncertainties of the different methods	11
Bibliography	12

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Foreword

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This document was prepared by Technical Committee ISO/TC 201, *Surface chemical analysis*, Subcommittee SC 4, *Depth profiling*.

This second edition cancels and replaces the first edition (ISO/TR 15969:2001), which has been technically revised.

The main changes compared to the previous edition are as follows:

- in the Scope, the applicable range of depth has been specified more clearly;
- Clause 3 has been revised according to the latest edition of the ISO 18115 series;
- in [4.2.2](#), the information on reference materials has been updated;
- [Table A.1](#) has been updated.

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